DESCRIPTION

PLANT CULTIVATION DEVICE

TECHNICAL FIELD

[0001]

The present technology relates to a plant cultivation apparatus used in a factory for cultivating vegetables or other plants.

BACKGROUND ART

[0002]

PTL 1 discloses a technology relating to a plant cultivation facility. The plant cultivation facility disclosed in PTL 1 includes a cultivation bed where plants are cultivated, a cultivation panel which includes a plurality of vent holes formed in a thickness direction of the panel, and overlaps with the cultivation bed on the side above the bed with a clearance left between the panel and the bed, and an air conditioning mechanism which introduces gas into the clearance between the cultivation bed and the cultivation panel.

Citation List

Patent Literature

[0003]

PTL 1: Unexamined Japanese Patent Publication No. 2012-28

SUMMARY OF THE INVENTION

[0004]

A plant cultivation apparatus according to ~~the present technology~~an aspect includes a cultivation shelf disposed in a cultivation space, and

including a plurality of cultivation units each including a cultivation bed and a cultivation plate disposed above the cultivation bed; an air conditioner disposed in an upper region of the cultivation space and configured to supply airflow toward the cultivation shelf; an induced draft fan configured to guide the airflow supplied from the air conditioner to a side of the cultivation shelf; and suction equipment disposed on the plurality of cultivation units and configured to suck the airflow through the side of the cultivation shelf, wherein each of the cultivation beds includes an air intake port through which the airflow is introduced by the suction equipment, and an air discharge port through which the airflow is guided to the corresponding cultivation plate, and each of the cultivation plates includes an air supply path formed inside, an air intake port through which the airflow introduced from the air discharge port of the corresponding cultivation bed is supplied to the air supply path, and an air discharge port formed in an upper surface of the corresponding cultivation plate, on which a cultivation plant is disposed, the air discharge port of each of the cultivation plates being configured to connect with the corresponding air supply path to supply the airflow to the cultivation plant from below. In an embodiment, a cultivation space where a cultivation environment is controllable,